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*Paula Faulk Hurley*  
Paula Faulk Hurley

25 August 2004

ATTY DOCKET: MXIC 1555-1

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application Inventor(s): Shu-Sing Liao Appl. No.: 10/801,954 Confirm. No.: 2359 Filed: 16 March 2004 Title: Method and System for Analyzing Defects of an Integrated Circuit Wafer	Group Art Unit: 2812 Examiner: Unassigned  <u>Customer No. 22470</u>
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Commissioner for Patents  
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Please change the country of the second inventor from CHINA to **REPUBLIC OF CHINA**.

Please change the location of the Assignee from Hsinchu, CHINA to **Hsinchu, Taiwan**.

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However, the Commissioner is hereby authorized to charge any additional fees that may be required by this paper, or to credit any overpayment to Deposit Account No. 50-0869 (MXIC 1555-1). This paper is submitted in duplicate.

Respectfully submitted,

*Warren S. Wolfeld*

Warren S. Wolfeld, Reg. No. 31,454

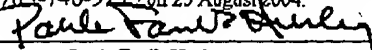
Dated: 25 August 2004

HAYNES BEFFEL & WOLFELD LLP  
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Appl. No.: 10/801,954	Examiner: Unassigned
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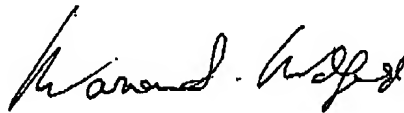
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APPL NO.	FILING OR 371 (c) DATE	ART UNIT	FIL FEE REC'D	ATTY. DOCKET NO	DRAWINGS	TOT CLMS	IND CLMS
10/801,954	03/16/2004	2812	1112	MXIC 1555-1	6	39	2

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CONFIRMATION NO. 2359

22470  
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## FILING RECEIPT



\*OC000000012862503\*

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## Applicant(s)

Shu-Sing Liao, Taichung City, ~~CHINA~~ Republic of China  
Szu-Tsun Ma, Hsinchu, ~~CHINA~~ Republic of China

## Assignment For Published Patent Application

Macronix International Co., Ltd., Hsinchu, ~~CHINA~~ TAIWAN

Domestic Priority data as claimed by applicant

Foreign Applications

If Required, Foreign Filing License Granted: 06/03/2004

Projected Publication Date: 09/22/2005

Non-Publication Request: No HAYNES BEFFEL &amp; WOLFELD LLP

Early Publication Request: No

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## Title

Method and system for analyzing defects of an integrated circuit wafer

Preliminary Class  
438

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